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IN THE UNITED STATES PATENT OFFICE

In re application of:  
David S. Pecora

Serial No.: 09/854,206

Filed: May 11, 2001

For: **ETCH OF SILICON NITRIDE SELECTIVE  
TO SILICON AND SILICON DIOXIDE  
USEFUL DURING THE FORMATION OF A  
SEMICONDUCTOR DEVICE**

§  
§ Group Art Unit: 1765 ✓  
§  
§ Examiner: Binh X. Tran  
§  
§ Atty. Docket: 00-0737.00/US  
§  
§ Paper No. 12  
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Date

*Anna Stafford*  
Signature

RESPONSE TO THE FINAL OFFICE ACTION OF JULY 8, 2003

Please enter the following in response to the Examiner's final office action mailed July 8, 2003 as paper no. 11.

Micron Technology, Inc.

00-0737.00/US